

- c) one or more process chambers disposable about the transfer chamber;
- d) a plumbing tray disposable adjacent the transfer chamber and having facility connections for each process chamber and load lock chamber; and
- e) a chamber tray disposable adjacent each process chamber, load lock chamber and transfer chamber, the chamber tray in fluid communication with the facility connections of the plumbing tray, wherein each process chamber is disposable on each chamber tray.

2. (Cancelled) A method of processing a substrate, comprising:
- introducing a substrate into a load lock chamber from atmospheric pressure;
 - degassing and/or pre-heating the substrate in the load lock chamber;
 - introducing the substrate into a transfer chamber; and
 - processing the substrate in one or more process chambers.
3. (Cancelled) The method of claim 2 further comprising:
- introducing the substrate into the load lock chamber;
 - cooling the substrate in the load lock chamber; and then
 - venting the load lock chamber to atmospheric pressure.
4. (Cancel) An apparatus for distributing facilities to devices on a processing system, comprising:
- an enclosure having at least one facility interface and at least one chamber interface; and
 - at least one manifold selected from the group consisting of a process gas manifold, vacuum manifold, water manifold and helium manifold disposed in the enclosure connected between the facility interface and the chamber interface.
5. (Cancel) An apparatus for distributing facilities, comprising:
- a support frame having one or more of an electronics box, a gas panel, a vacuum line and a controller device disposed thereon.

6. (Cancelled) A method of processing substrates, comprising:
 - a) positioning a pair of substrates on two blades on separate robots in a processing system;
 - b) moving the substrates in parallel to a pair of first process chambers; and then
 - c) moving the substrates in parallel to a pair of second process chambers.
7. The apparatus of claim 1, wherein the transfer chamber comprises one or more process access ports.
8. The apparatus of claim 7, wherein the transfer chamber comprises at least six process access ports.
9. (Cancel) The apparatus of claim 1, wherein the process chamber is disposable on the chamber tray.
10. (Cancel) The apparatus of claim 7, wherein the process chamber and the chamber tray form a modular unit.
11. (Amended) The apparatus of claim 28, wherein the modular unit is mounted to the transfer chamber at the access port.
12. The apparatus of claim 1, wherein the chamber tray is mounted separately to the transfer chamber.
13. The apparatus of claim 1, wherein the process chamber and the chamber tray are mounted to a support frame.
14. The apparatus of claim 13, wherein the support frame comprises rollable support members.

15. The apparatus of claim 1, wherein the chamber tray comprises an enclosure having one or more selected from the group consisting of a pneumatic distribution manifold, process gas manifold, vacuum manifold, water manifold, and helium manifold.
16. The apparatus of claim 15, wherein the enclosure comprises a plurality of facility connections disposed thereon that are in fluid communication with the facility connections of the plumbing tray.
17. (Cancel) The apparatus of claim 1, wherein the plumbing tray is disposed underneath the transfer chamber.
18. The apparatus of claim 1, wherein the transfer chamber comprises at least one transfer means for moving work pieces to and from the load lock and process chambers.
19. The apparatus of claim 18, wherein the transfer means is a robot.
20. The apparatus of claim 19, wherein the transfer chamber comprises two transfer robots.
21. The apparatus of claim 20, wherein the transfer chamber further comprises at least one lift, the lift comprising a support shaft, pedestal, lift assembly, and rotational assembly.
22. The apparatus of claim 21, wherein the lift is rotatable to maintain an orientation of the work pieces as the work pieces pass between the transfer robots.
23. (Cancel) An apparatus for distributing facilities to devices on a processing system comprising an enclosure having a plurality of facility interfaces and a plurality of chamber interfaces disposed about a perimeter thereof.

24. (Cancel) The apparatus of claim 23, wherein the enclosure comprises a plurality of conduits disposed therein.

25. (Cancel) The apparatus of claim 24, wherein the conduits comprise at least one facility selected from the group consisting of a process gas manifold, vacuum manifold, water manifold and helium manifold.

26. (Cancel) The apparatus of claim 24, wherein the conduits are connected between the facility interface and the chamber interface.

27. (Cancel) The apparatus of claim 23, wherein each facility interface is in communication with one or more facility sources.

Please add the following new claims 28 and 29:

28. (New) An apparatus for processing substrates, comprising:
a) a transfer chamber comprising one or more process access ports;
b) one or more load lock chambers disposable about the transfer chamber;
c) one or more process chambers disposable about the transfer chamber;
d) a plumbing tray disposable adjacent the transfer chamber and having facility connections for each process chamber and load lock chamber; and
e) a chamber tray disposable adjacent each process chamber, load lock chamber and transfer chamber, wherein the chamber tray is in fluid communication with the facility connections of the plumbing tray, and wherein each process chamber and each chamber tray form a modular unit.

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29. (New) An apparatus for processing substrates, comprising:
a) a transfer chamber;
b) one or more load lock chambers disposable about the transfer chamber;
c) one or more process chambers disposable about the transfer chamber;
d) a plumbing tray disposable underneath the transfer chamber having facility connections for each process chamber and load lock chamber; and

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